

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1291	(702/81-85).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:02
L2	728	(702/117,121).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:08
L3	570	(702/155,166,170,172).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:08
L4	1068	(702/182).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:08
L5	878	(702/183).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:14
L6	997	(356/128,601,609,612).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:15
L7	733	(356/626,630,635).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:19
L8	715	(438/5,7).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:20
L9	1992	(438/14).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:34
L10	828	L9 and (optical (feed adj forward))	US-PGPUB; USPAT	OR	ON	2005/11/30 13:34
L11	902	(438/16).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:51
L12	610	(700/108).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:53
L13	598	(700/109,110).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:53
L14	1394	(700/121).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/11/30 13:54
L15	2	optical adj metrology and feed adj forward and @pd>"20050524"	US-PGPUB; USPAT; EPO; JPO; DERWENT ; IBM_TDB	OR	ON	2005/11/30 14:07
L16	6	optical adj metrology and downstream and @pd>"20050524"	US-PGPUB; USPAT; EPO; JPO; DERWENT ; IBM_TDB	OR	ON	2005/11/30 14:08
L17	0	(wafer microelectronic semiconductor) near (fabrication manufacture manufacturing) and feed adj foward	US-PGPUB; USPAT; EPO; JPO; DERWENT ; IBM_TDB	OR	ON	2005/11/30 14:09
L18	30	(wafer microelectronic semiconductor) near (fabrication manufacture manufacturing) and downstream with (parameter measurement) and @pd>"20050524"	US-PGPUB; USPAT; EPO; JPO; DERWENT ; IBM_TDB	OR	ON	2005/11/30 14:09
L19	0	optical adj metrology and three adj dimensional adj characterization and @pd>"20050524"	US-PGPUB; USPAT; EPO; JPO; DERWENT ; IBM_TDB	OR	ON	2005/11/30 14:12
L20	0	(wafer microelectronic semiconductor) near (fabrication manufacture manufacturing) and metrology same three adj dimensional adj characterization and @pd>"20050524"	US-PGPUB; USPAT; EPO; JPO; DERWENT ; IBM_TDB	OR	ON	2005/11/30 14:12
L21	2	(wafer microelectronic semiconductor) near (fabrication manufacture manufacturing) and three adj dimensional adj characterization and @pd>"20050524"	US-PGPUB; USPAT; EPO; JPO; DERWENT ; IBM_TDB	OR	ON	2005/11/30 14:12

L22	159	optical adj metrology and multiple adj wavelengths	US-PGPUB; USPAT; EPO; JPO; DERWENT ; IBM_TDB	OR	ON	2005/11/30 14:14
L23	18	optical adj metrology and spectrometer and @pd>"20050524"	US-PGPUB; USPAT; EPO; JPO; DERWENT ; IBM_TDB	OR	ON	2005/11/30 14:20